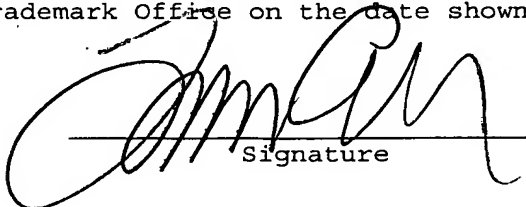


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CERTIFICATION OF MAILING OR TRANSMISSION

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 or facsimile transmitted to the U.S. Patent and Trademark Office on the date shown below.

  
SignatureJanuary 4, 2005  
DateIN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/675,049 Confirmation No: 5871  
Applicant : Ioannis Dotsikas  
Filed : September 30, 2003  
Title : METHOD AND FURNACE FOR THE VAPOR PHASE  
DEPOSITION OF COMPONENTS ONTO SEMICONDUCTOR  
SUBSTRATES WITH A VARIABLE MAIN FLOW DIRECTION  
OF THE PROCESS GAS  
Art Unit : 2818  
Examiner : Renee R. Berry  
Docket No. : MUH-12818  
Customer No. : 24131

**AMENDMENT**

Hon. Commissioner for Patents  
P.O. Box 1459  
Alexandria, VA 22313-1450

S i r :

Responsive to the Office action dated October 4, 2004 kindly  
amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of  
claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 7 of this paper.